

IN THE CLAIMS

Please amend the claims as follows:

1. (Currently Amended) A method for detecting conditions in an electronic device fabrication facility, comprising:
 - measuring fabrication data;
 - determining the route a workpiece follows during fabrication;
 - storing measured data relevant to the route the workpiece followed during fabrication in a data set of the workpiece;
 - analyzing the data set of the workpiece; and
 - determining current conditions using the analysis.
 - ~~examining the analysis.~~
2. (Previously Presented) The method of claim 1, wherein the route a particular workpiece follows is a subset of the entire manufacturing process.
3. (Previously Presented) The method of claim 1, wherein determining includes;
 - identifying operations that are linked in some manner;
 - determining subdivisions of the identified operations; and
 - developing a listing of all possible routes through the subdivisions of the operations that workpieces may traverse during fabrication.
4. (Previously Presented) The method of claim 3, wherein operations includes machines, chambers, processes associated with the route the workpiece follows.
5. (Original) The method of claim 3, wherein the manner of linking is by physical location.
6. (Original) The method of claim 3, wherein the manner of linking is by machine type.
7. (Original) The method of claim 3, wherein the manner of linking is by time of processing.

8. (Original) The method of claim 3, wherein the linking is by any other condition relevant to the fabrication process.
9. (Previously Presented) The method of claim 3, wherein the determining the subdivisions includes identifying all parts of the operation, machine, process, chamber and the like that have a substantially similar end product.
10. (Previously Presented) The method of claim 3, wherein all possible routes only includes probable routes through the subdivisions.
11. (Currently Amended) A method for detecting conditions in an electronic device fabrication facility, comprising:
- determining the route a workpiece followed during fabrication;
 - separately for each route, measuring fabrication data items relevant to that route;
 - storing measured data relevant to the route the workpiece followed during fabrication in a data set of the workpiece;
 - analyzing the data set of the workpiece; and
 - ~~examining the analysis~~ determining current conditions using the analysis.
12. (Original) The method of claim 11, wherein the fabrication data items are measured from production data sources.
13. (Original) The method of claim 12, wherein the production data source is a test probe.
14. (Original) The method of claim 12, wherein the production data source is a parametric measuring device.
15. (Original) The method of claim 12, wherein the production data source is one in which film thickness is being measured.

16. (Original) The method of claim 12, wherein the production data source is one in which critical dimensions are being measured.

17. (Original) The method of claim 12, wherein the production data source includes any other data source that is relevant to the fabrication process and its condition.

18. (Currently Amended) A method for detecting conditions in an electronic device fabrication facility, comprising:

- determining the exact route a workpiece actually followed during fabrication;
- separately for each route, measuring fabrication data relevant to that route;
- storing measured data relevant to the route the workpiece actually followed during fabrication in a data set of the workpiece in a data processing device;
- analyzing the data set of the workpiece; and
- examining the analysis to determine current conditions.

19. (Previously Presented) The method of claim 18, wherein measured data relevant to the route a workpiece actually followed during fabrication is relevant based on physical proximity to the route.

20. (Previously Presented) The method of claim 18, wherein measured data relevant to the route a workpiece actually followed during fabrication is relevant based manufacturing result.

21. (Original) The method of claim 18, wherein the data processing device is a computer system containing a relational database on a storage device and executed on a processor.

22. (Previously Presented) The method of claim 18, wherein storing measured data in a data processing device includes:

- adding a data item from the measured route fabrication data to the data set of the workpiece; and

relating the added data item to the previously stored data items by some point of data commonality.

23. (Original) The method of claim 22, wherein the point of data commonality is based on time.

24. (Currently Amended) A method for detecting conditions in an electronic device fabrication facility, comprising:

- determining the exact route a workpiece actually followed during fabrication;
- separately for each route, measuring fabrication data relevant to that route;
- storing measured data relevant to the route the workpiece actually followed during fabrication in a data set of the workpiece in a data processing device;
- analyzing the data set of the workpiece; and
- ~~examining the analysis~~ determining current conditions using the analysis.

25. (Original) The method of claim 24, wherein the analysis is a statistical analysis.

26. (Original) The method of claim 24, wherein the analysis is a trend analysis.

27. (Original) The method of claim 24, wherein the analysis is a correlation study.

28. (Original) The method of claim 24, wherein examining includes comparing the analysis of the data set of the workpiece to expected conditions.

29. (Currently Amended) A method for responding to conditions in an electronic device fabrication facility, comprising:

- measuring fabrication data;
- determining the route a workpiece followed during fabrication;
- storing measured data relevant to the route the workpiece followed during fabrication in a data set of the workpiece;
- analyzing the data set of the workpiece;

determining current conditions using the analysis;

comparing the current conditions ~~analysis~~ to expected conditions; and
responding to the comparison.

30. (Previously Presented) The method of claim 29, wherein the route the workpiece followed is a subset of the entire manufacturing process.

31. (Previously Presented) The method of claim 29, wherein determining includes;
identifying operations that are linked in some manner;
determining subdivisions of the identified operations; and
developing a listing of all possible routes through the subdivisions of the operations that workpieces may traverse during fabrication.

32. (Previously Presented) The method of claim 31, wherein operations includes machines, chambers, processes associated with the route the workpiece followed.

33. (Original) The method of claim 31, wherein the manner of linking is by physical location.

34. (Original) The method of claim 31, wherein the manner of linking is by machine type.

35. (Original) The method of claim 31, wherein the manner of linking is by time of processing.

36. (Original) The method of claim 31, wherein the linking is by any other condition relevant to the fabrication process.

37. (Previously Presented) The method of claim 31, wherein the determining the subdivisions includes identifying all parts of the operation, machine, process, chamber and the like that have a substantially similar end product.

38. (Previously Presented) The method of claim 31, wherein all possible routes only includes probable routes through the subdivisions.

39. (Currently Amended) A method for responding to conditions in an electronic device fabrication facility, comprising:

- determining each route one or more workpieces follows during fabrication;
- separately for each route, measuring fabrication data items relevant to that route;
- determining the route a particular workpiece followed during fabrication;
- storing measured data items relevant to the route the particular workpiece followed during fabrication in a data set of the workpiece;
- analyzing the data set of the particular workpiece;
- determining current conditions using the analysis;
- comparing the current conditions analysis to expected conditions; and
- responding to the comparison.

40. (Original) The method of claim 39, wherein the fabrication data items are measured from production data sources.

41. (Original) The method of claim 40, wherein the production data source is a test probe.

42. (Original) The method of claim 40, wherein the production data source is a parametric measuring device.

43. (Original) The method of claim 40, wherein the production data source is one in which film thickness is being measured.

44. (Original) The method of claim 40, wherein the production data source is one in which critical dimensions are being measured.

45. (Currently Amended) A method for responding to conditions in an electronic device fabrication facility, comprising:

- determining each route one or more workpieces follows during fabrication;
- separately for each route, measuring fabrication data items relevant to that route;
- determining the exact route a particular workpiece actually followed during fabrication;
- storing measured data items relevant to the route the particular workpiece actually followed during fabrication in a data set of the particular workpiece in a data processing device;
- analyzing the data set of the particular workpiece;
- determining current conditions using the analysis
- comparing the current conditions analysis to expected conditions; and
- responding to the comparison.

46. (Previously Presented) The method of claim 45, wherein measured data items relevant to the route the particular workpiece actually followed during fabrication is relevant based on physical proximity to the route.

47. (Previously Presented) The method of claim 45, wherein measured data items relevant to the route the particular workpiece actually followed during fabrication is relevant based on manufacturing result.

48. (Original) The method of claim 45, wherein the data processing device is a computer system containing a relational database on a storage device and executed on a processor.

49. (Previously Presented) The method of claim 45, wherein storing measured-data items in a data processing device includes:

- adding a data item from the measured route fabrication data items relevant to that route to the data set of the particular workpiece; and
- relating the added data item to the previously stored data items by some point of data commonality.

50. (Original) The method of claim 49, wherein point of data commonality is based on time.

51. (Currently Amended) A method for responding to conditions in an electronic device fabrication facility, comprising:

- determining each route one or more workpieces follows during fabrication;
- separately for each route, measuring fabrication data items relevant to that route;
- determining the exact route a particular workpiece actually followed during fabrication;
- storing measured data items relevant to the route the particular workpiece actually followed during fabrication in a data set of the particular workpiece in a data processing device;
- performing an analysis on the data set of the particular workpiece on a data processing device;

- determining current conditions using the analysis

- non-manually comparing the current conditions ~~analysis~~ to expected conditions; and
- responding to the comparison.

52. (Original) The method of claim 51, wherein the analysis is a statistical analysis.

53. (Original) The method of claim 51, wherein the analysis is a trend analysis.

54. (Original) The method of claim 51, wherein the analysis is a correlation study.

55. (Original) The method of claim 51, wherein responding includes:

- alerting a user when the comparison shows an unexpected condition.

56. (Original) The method of claim 55, wherein the alerting is by visual cues on an output device of the data processor.

57. (Original) The method of claim 55, wherein the alerting is by the data processor sending a message to the user of an unexpected condition.

58. (Original) The method of claim 55, wherein the data processing device non-manually halts production when an unexpected condition occurs.

59. (Original) The method of claim 51, wherein responding includes:

not alerting a user when the comparison shows expected conditions in the fabrication facility.

60. (Original) The method of claim 51, wherein responding includes:

non-manually continuing fabrication when the comparison shows expected conditions in the fabrication facility.